

Advancing nanoscale characterization of semiconductor devices by effortless 4D-STEM workflows

Daniel Nemecek, PhD

TESCAN ORSAY HOLDING

IRSP, April 2023

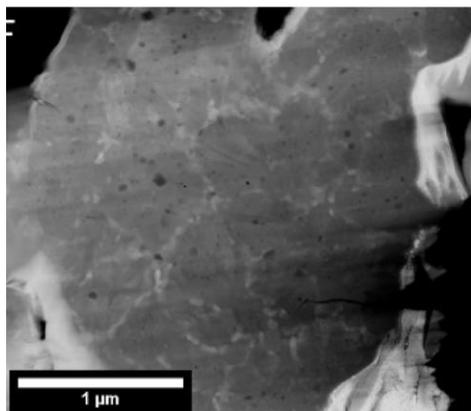
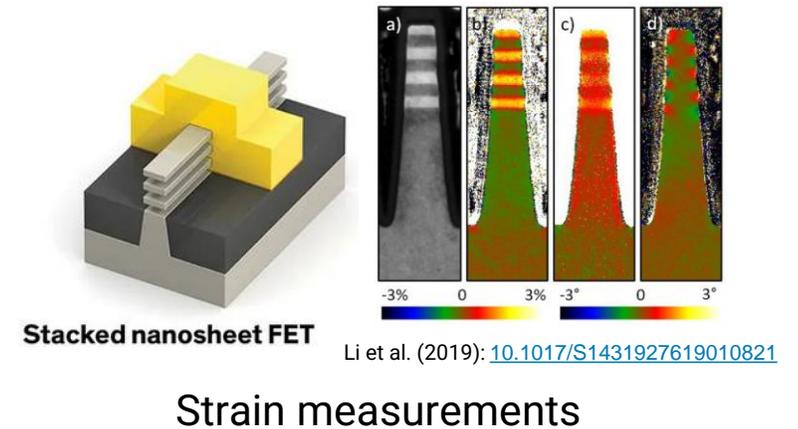


PRESENTATION OUTLINE

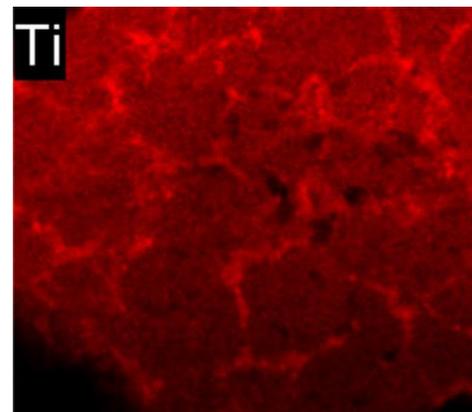
- Motivation and introduction of 4D-STEM analytical techniques
- Improving accuracy of diffraction measurements with beam precession
- Strain analysis and orientation mapping using 4D-STEM measurements
- Improving sensitivity of phase/orientation mapping with multimodal analysis
- Characterization of a semiconductor device by 4D-STEM measurements
- Effortless 4D-STEM measurements provided by state-of-the-art technology and automation

DRIVERS FOR NANOSCALE CHARACTERIZATION

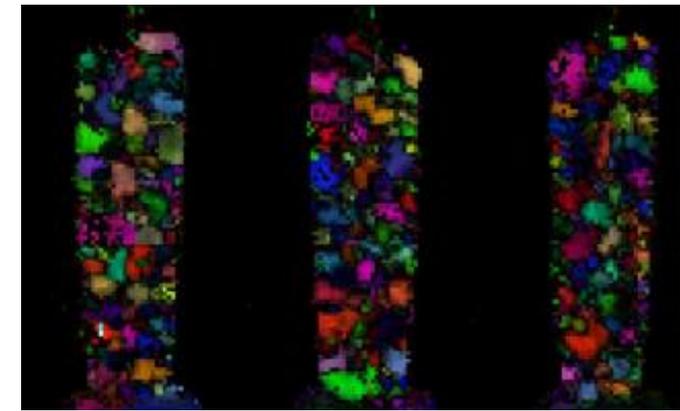
- Development of new and improved nanostructures and devices
- Material properties given by both composition and structure
- Grain size and distribution affected by production process
- Strain engineering and failure analysis in semicon devices



Nanoscale imaging



Compositional analysis

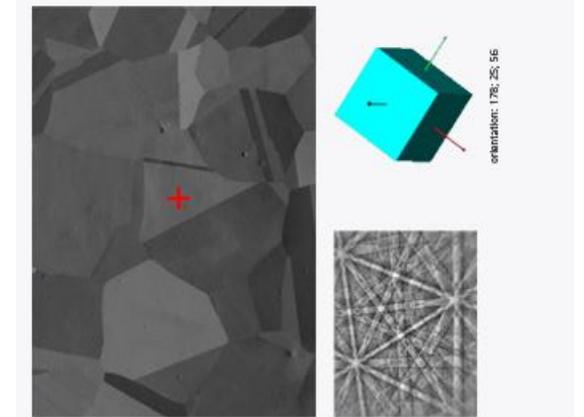
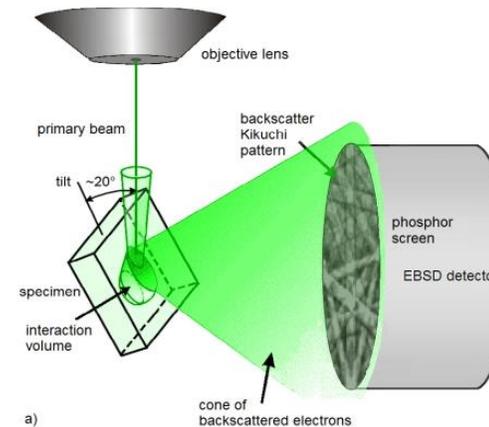


Grain size and orientation

TRADITIONAL TECHNIQUES FOR PHASE AND ORIENTATION ANALYSIS

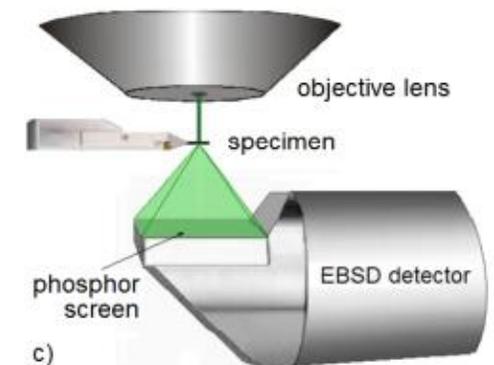
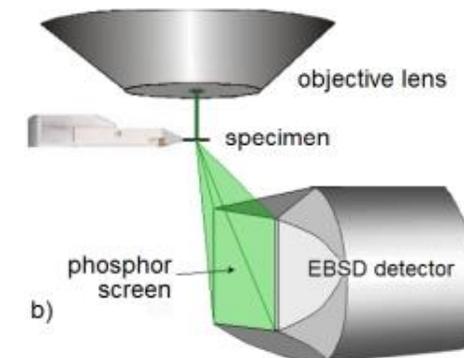
Electron Backscatter Diffraction (EBSD)

- Employs Kikuchi lines from back scattered electrons
- Specimen must be tilted, requires large probe current
- High angular resolution and large FOV possible
- Spatial resolution is limited to 25-100 nm



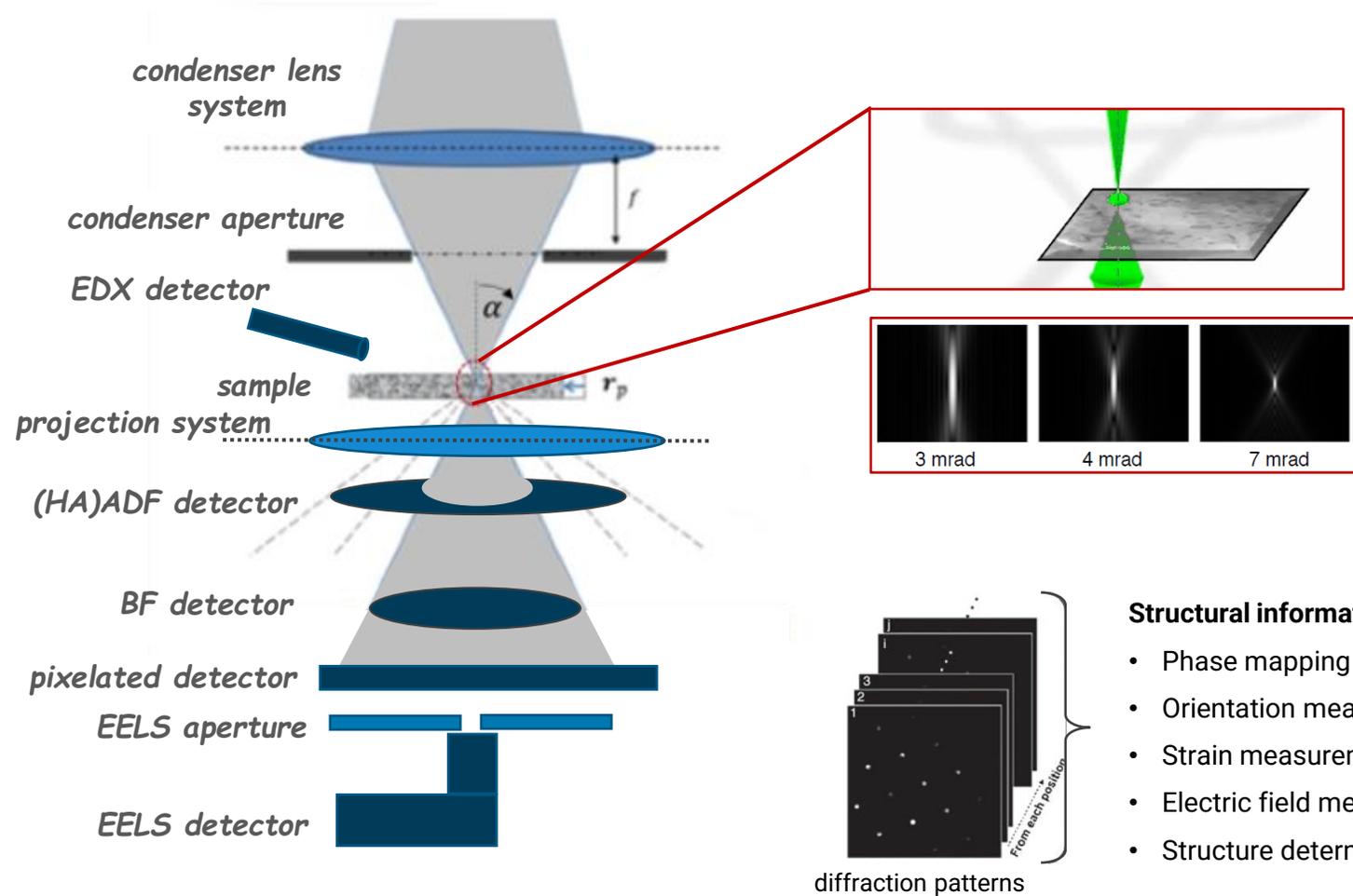
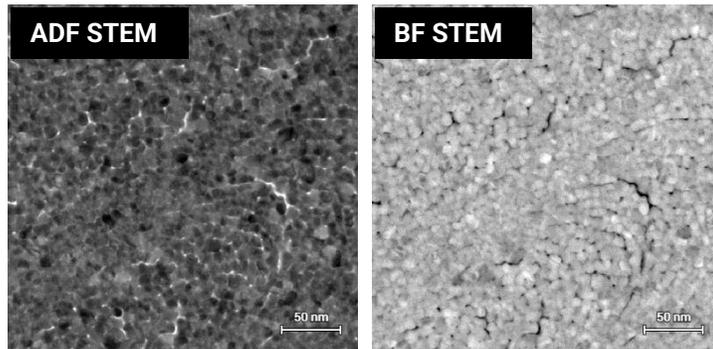
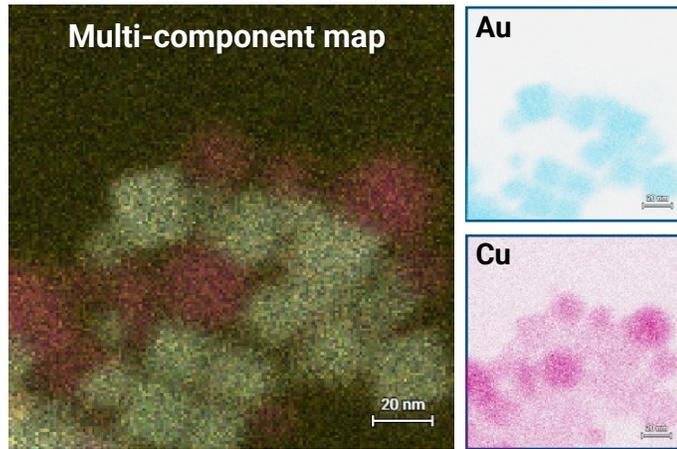
Transmission Kikuchi Diffraction (TKD)

- Employs Kikuchi lines from transmitted electrons
- Specimen is not tilted, smaller working distance
- Requires very thin specimen (transparent at 30 kV)
- Spatial resolution is improved to 5-10 nm



ANALYTICAL SCANNING TRANSMISSION ELECTRON MICROSCOPY

Breaking to <5 nm resolution range



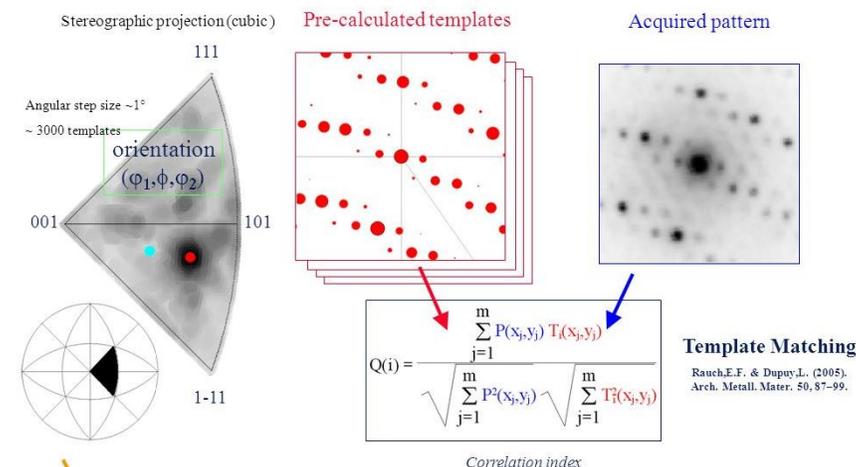
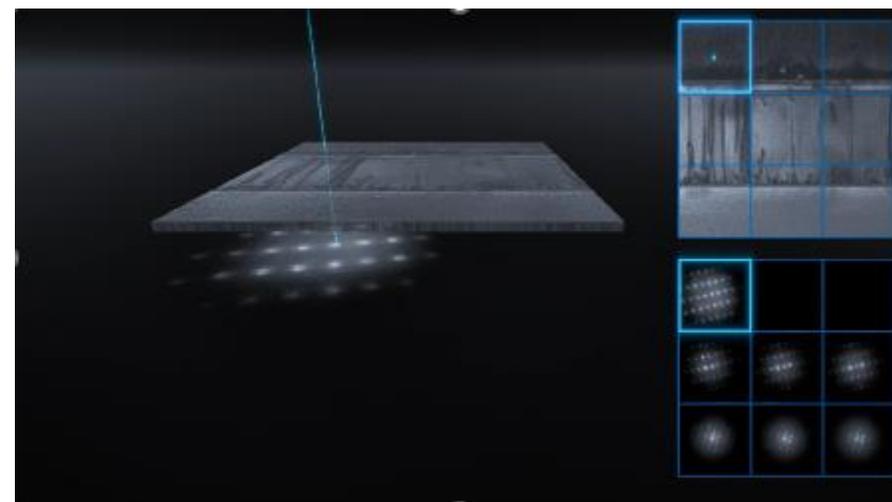
Structural information

- Phase mapping
- Orientation measurements
- Strain measurements
- Electric field measurements
- Structure determination

PHASE AND ORIENTATION ANALYSIS USING 4D-STEM

Automated crystallographic orientation mapping

- Employs NBED of transmitted electrons
- Specimen is not specifically tilted
- High angular resolution and large FOV possible
- Spatial resolution 1-4 nm when using FEG STEM
- Template matching of experimental diffraction patterns
- Requires known structural file(s) for template generation
- Improvement of template matching with beam precession (typically using the ASTAR module from NanoMEGAS)



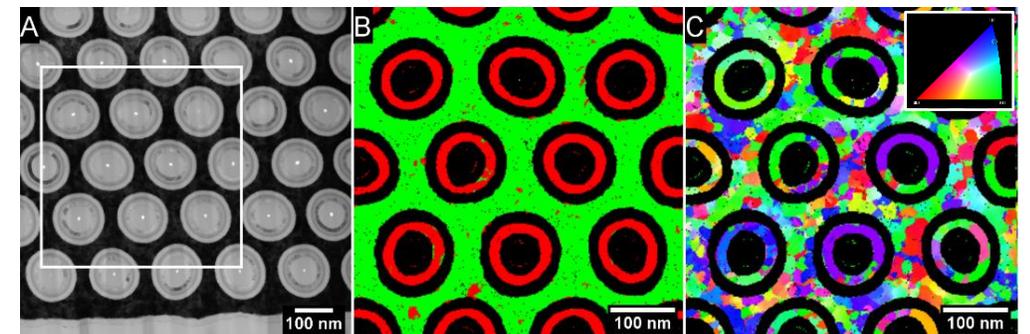
Sources: Nanomegas.com

Rauh E. et al. (2005): [10.1002/mawe.200500923](https://doi.org/10.1002/mawe.200500923)

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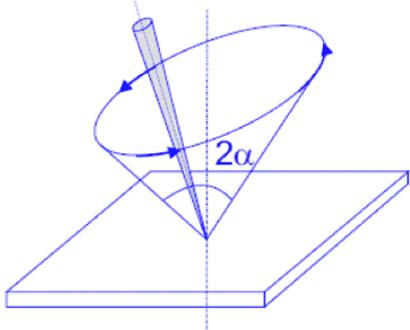


Phase and orientation analysis of 3D-NAND devices

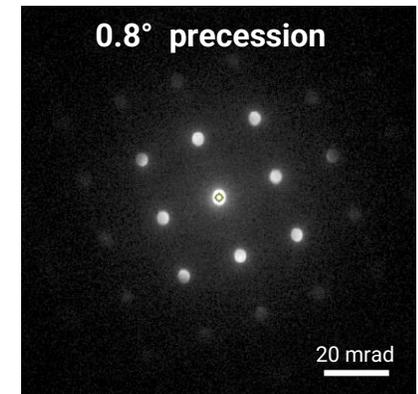
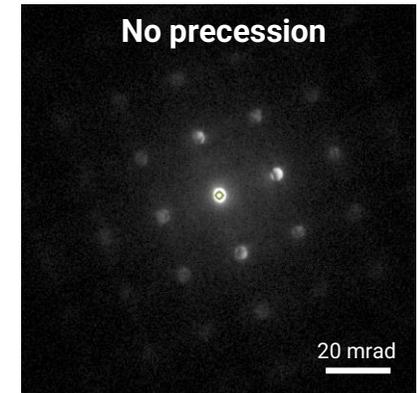
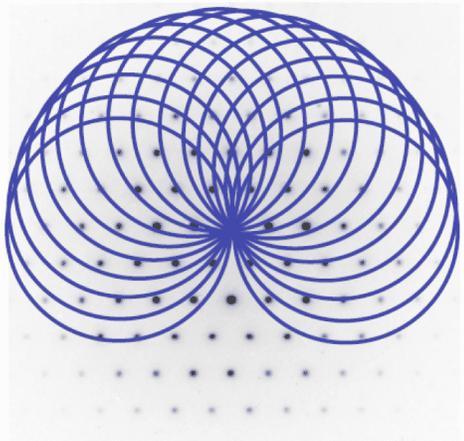
Sources: Nanomegas.com

Rauch E. et al. (2005): [10.1002/mawe.200500923](https://doi.org/10.1002/mawe.200500923)

INCREASING ACCURACY BY BEAM PRECESSION



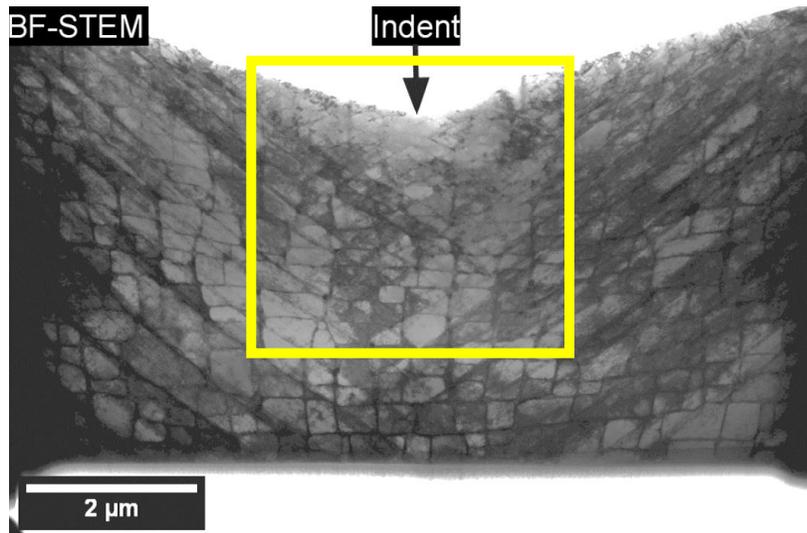
Precession Microdiffraction



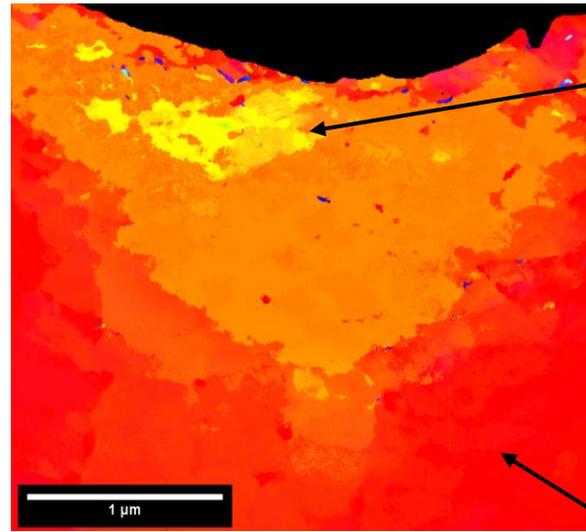
- Intensity within spots is more homogeneous and Kikuchi lines are averaged out
- Higher order Bragg spots are excited and observed in diffraction patterns
- Observed spot intensities correspond better to kinematical intensities

ORIENTATION AND STRAIN MAPPING WITH BEAM PRECESSION

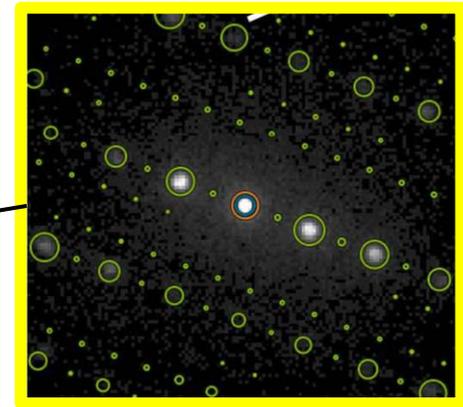
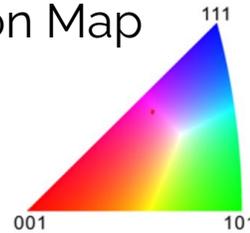
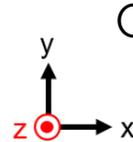
Deformation behavior in Ni-based superalloys



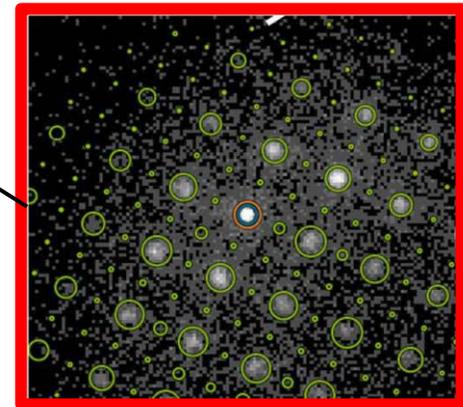
STEM BF Image



Orientation Map



Re-oriented to [103]



Undeformed [001]

BENEFITS OF BEAM PRECESSION

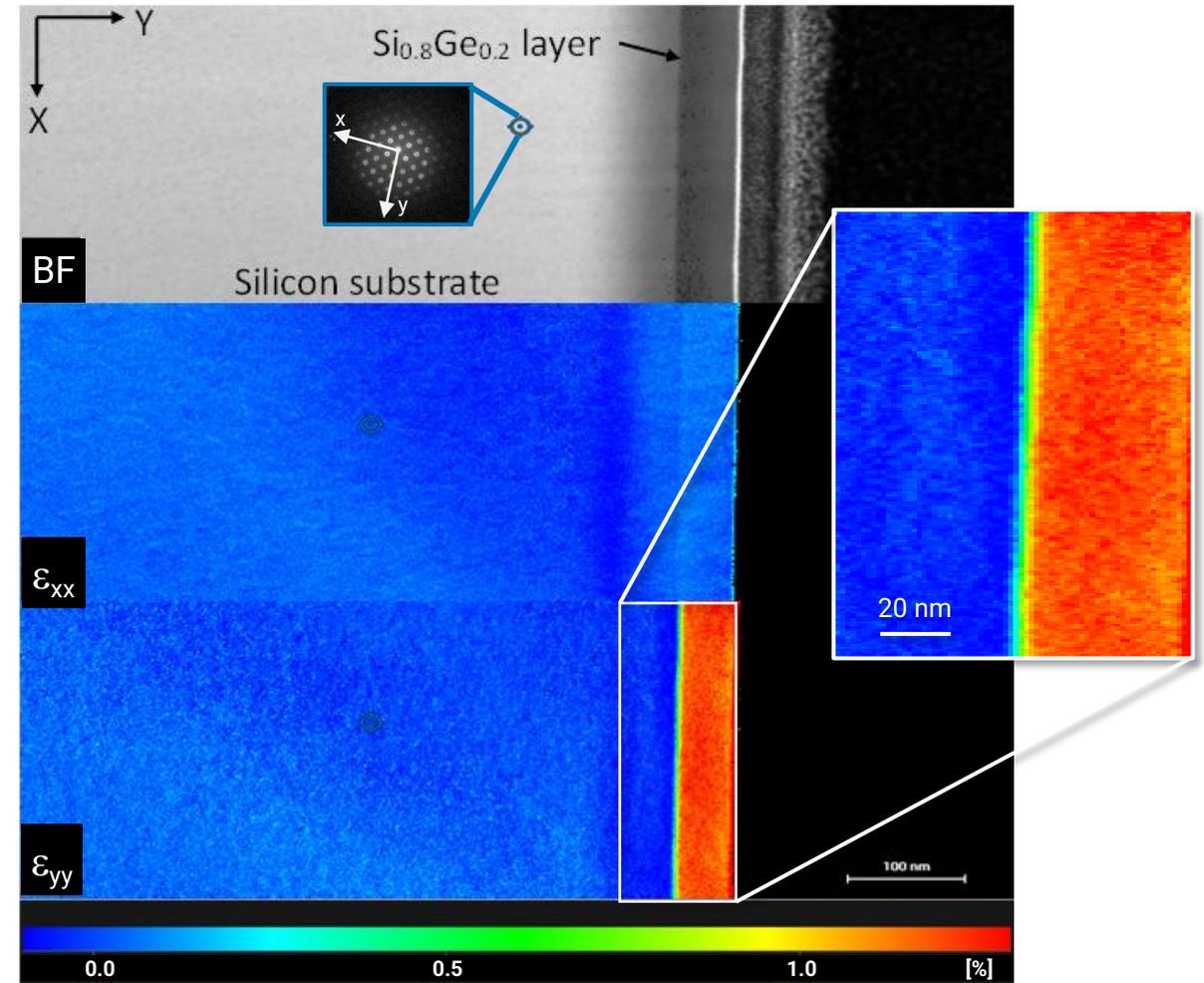
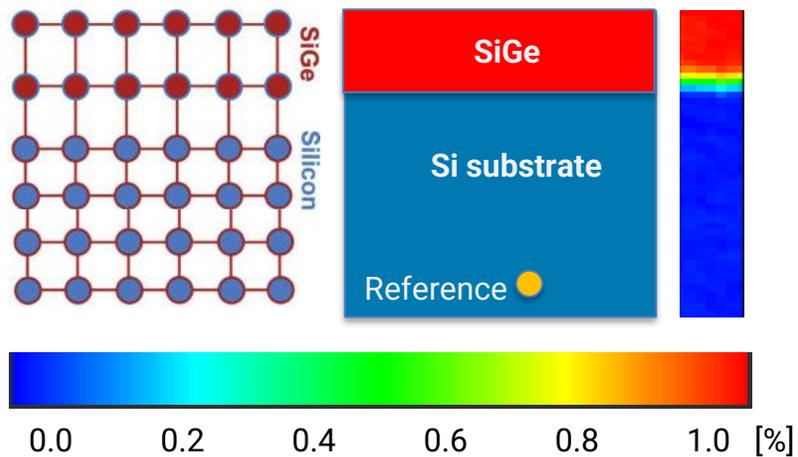
- **Orientation mapping**
 - Higher resolution spots enable a higher angular resolution
 - Better matching of kinematical templates with acquired data

- **Strain mapping**
 - Higher resolution spots are more sensitive to strain and improve strain precision
 - Better identification of spots and their central positions improves strain precision

- **Implications for non-ideal specimen**
 - Results are less sensitive to the thickness variations (uneven specimen)
 - Results are less sensitive to slight misorientation from the zone axis (bent specimen)

STRAIN MEASUREMENT USING NBED WITH BEAM PRECESSION

- Strain between different crystal lattices
- Strain engineering and failure analysis
- Direct measurement of diff. spot displacement
- 2-4 nm spatial resolution (using FEG STEM)
- High precision with beam precession

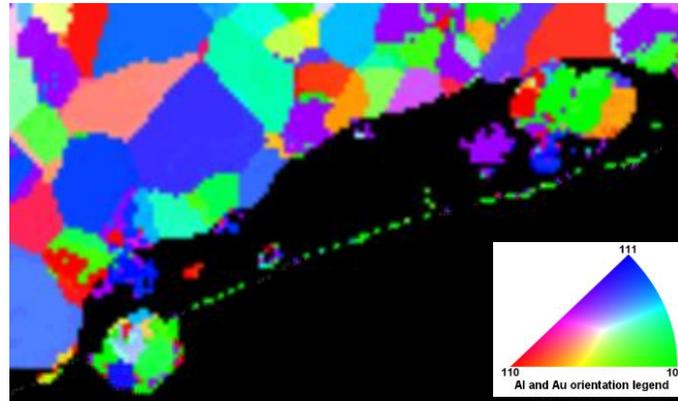


IMPROVING ACCURACY OF PHASE MAPPING WITH EDS

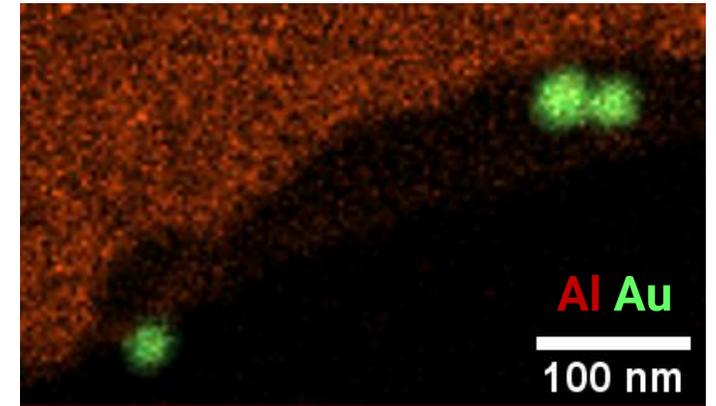
Analysis of phases with lattice parameter difference <5%



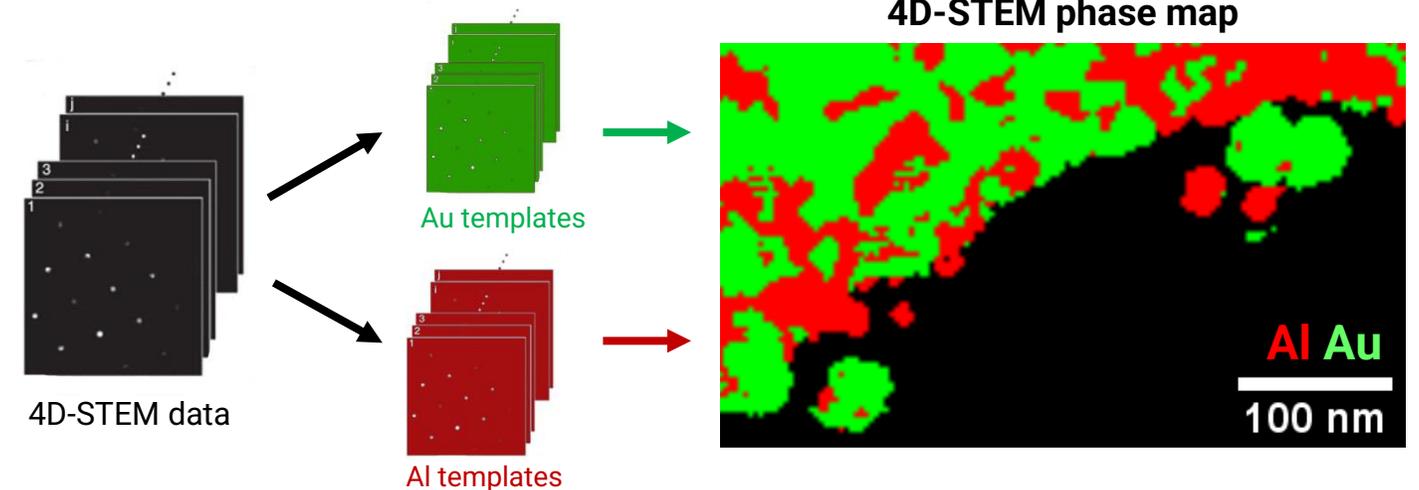
4D-STEM orientation mapping (Au, Al)



EDS elemental map



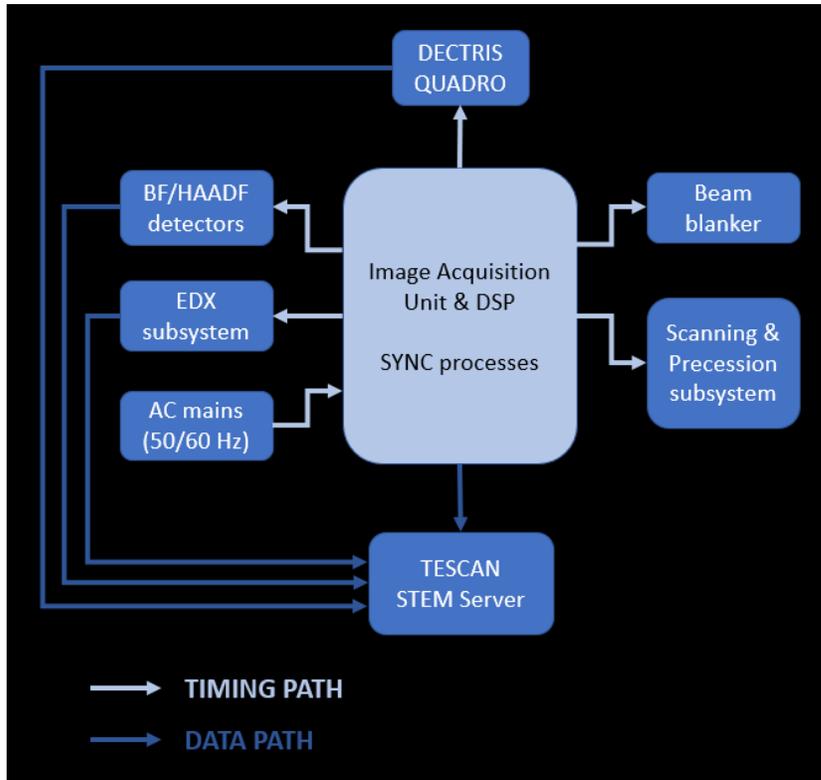
4D-STEM phase map



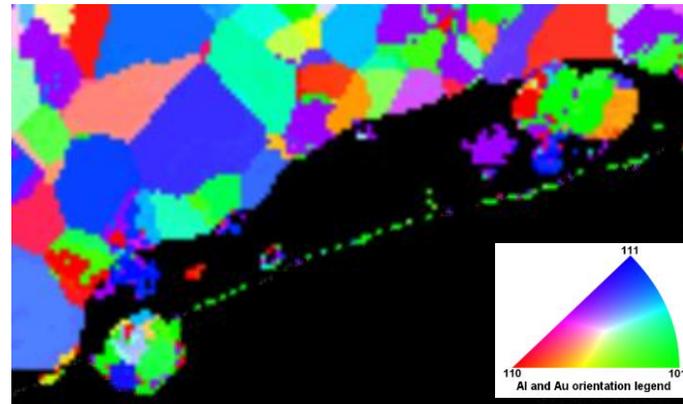
IMPROVING ACCURACY OF PHASE MAPPING WITH EDS

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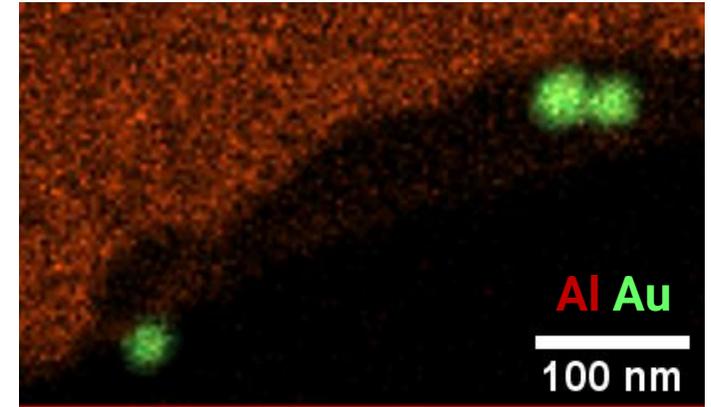
Synchronization of multimodal data readout



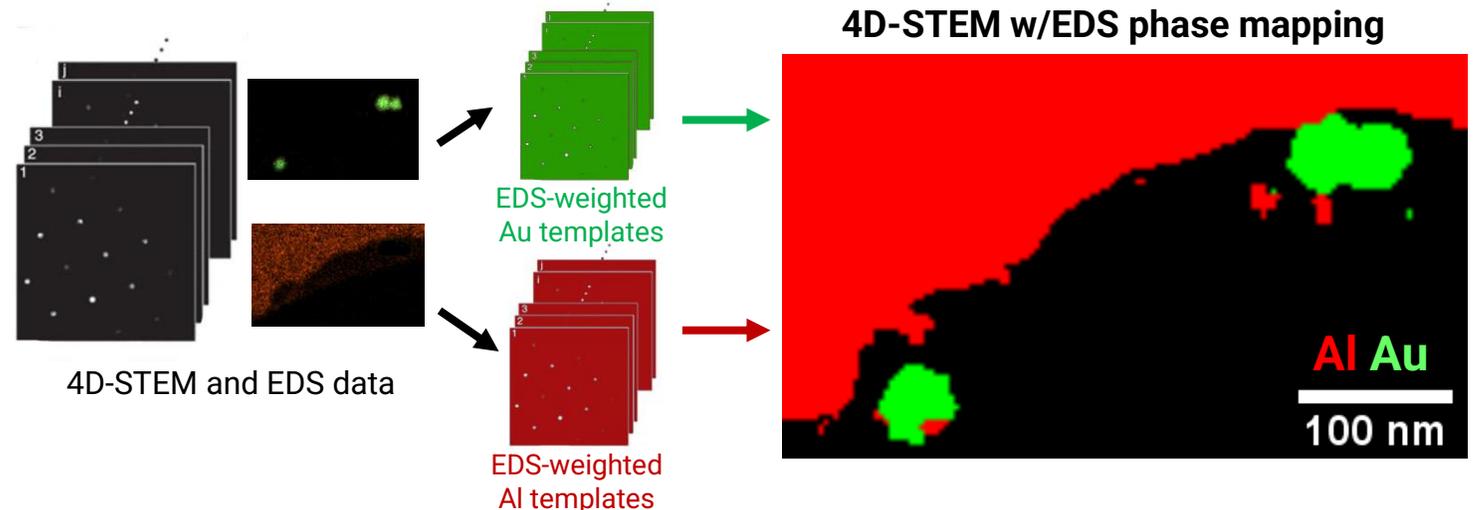
4D-STEM orientation mapping (Au, Al)



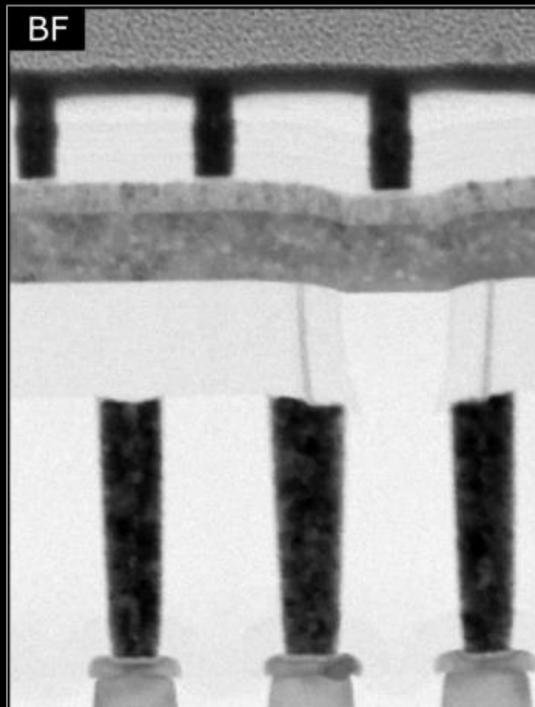
EDS elemental map



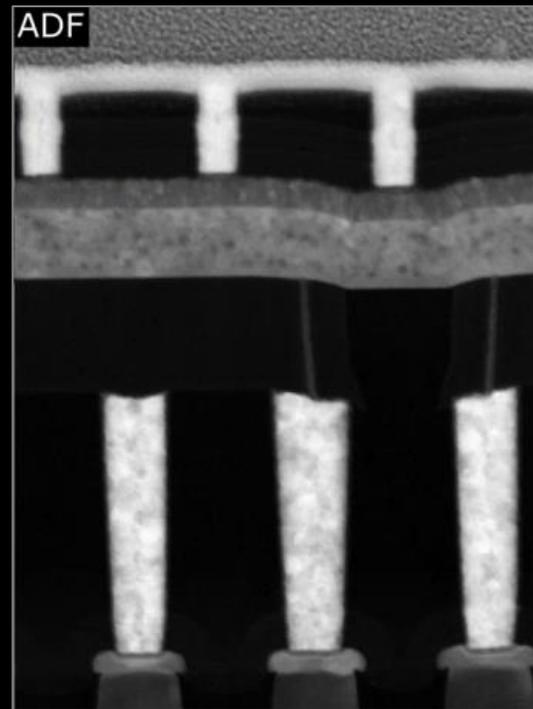
4D-STEM w/EDS phase mapping



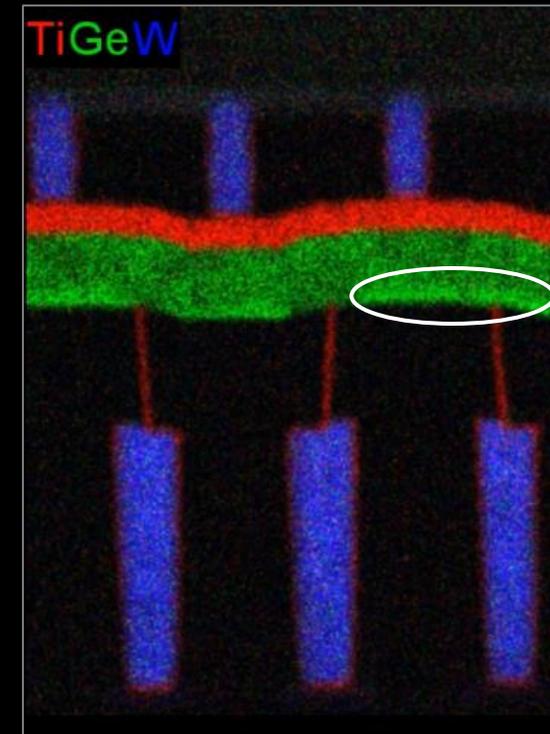
CHARACTERIZATION OF A SEMICONDUCTOR DEVICE



BF imaging



DF imaging



EDS mapping

CHARACTERIZATION OF A SEMICONDUCTOR DEVICE

4D-STEM measurement

- probe size: 1.15 nm
- conv. angle: 2 mrad
- precession: 0.8°
- pixel size: 2.0 nm
- diff. size: 120 mrad

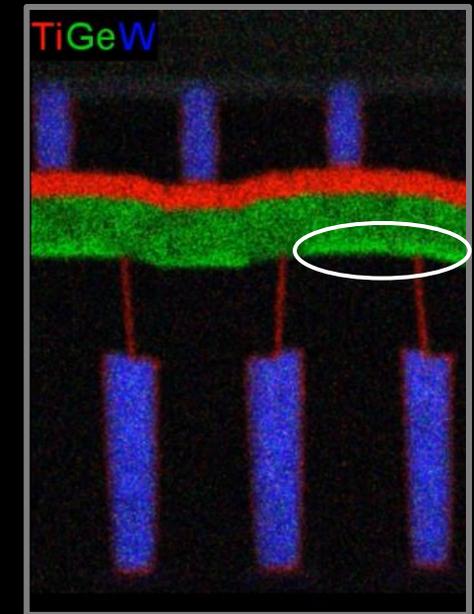
4D-STEM analysis

- 5 cubic templates
- 3 amorphous templates
- Postprocessing in ACOM
- 12 mins using 7 cores



4D-STEM phase mapping

Pt
 TiN
 GeSbTe
 Ge
 amo 1
 amo 2
 W
 Si



EDS mapping

A STEM THAT IS AS EASY TO USE AS A SEM



"I am proud of our group, in Brno and Tempe."

We have taken a very complicated instrument and turned it into something that anyone can use. It is a great example of expert systems automation and user experience design.

JK Weiss,

Applications Development Manager
and General Manager of TESCAN Tempe

A STEM THAT IS AS EASY TO USE AS A SEM

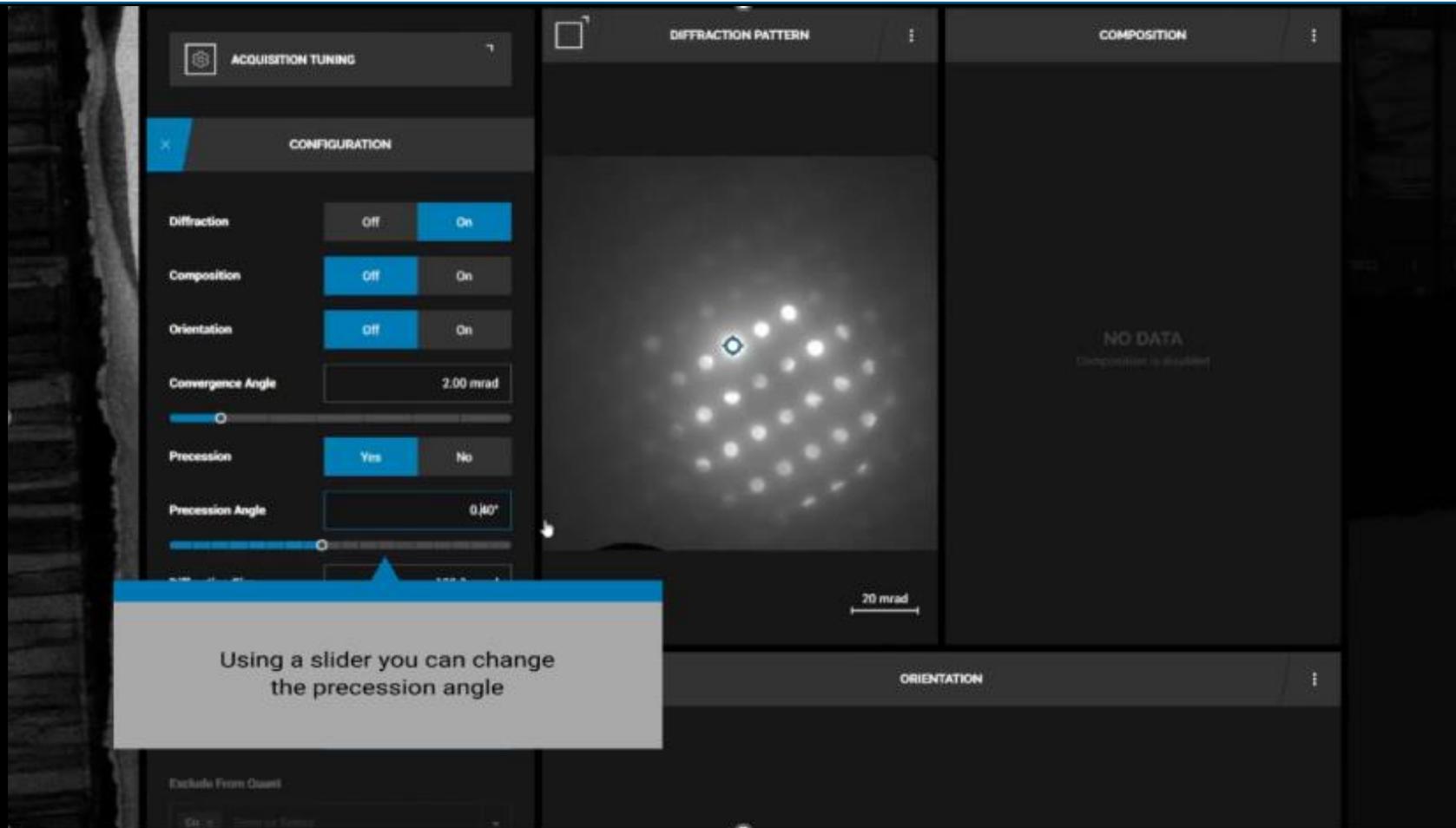


A contemporary 4D-STEM setup



TESCAN TENSOR integrated solution

A STEM THAT IS AS EASY TO USE AS A SEM



Select a Region of Interest (ROI)

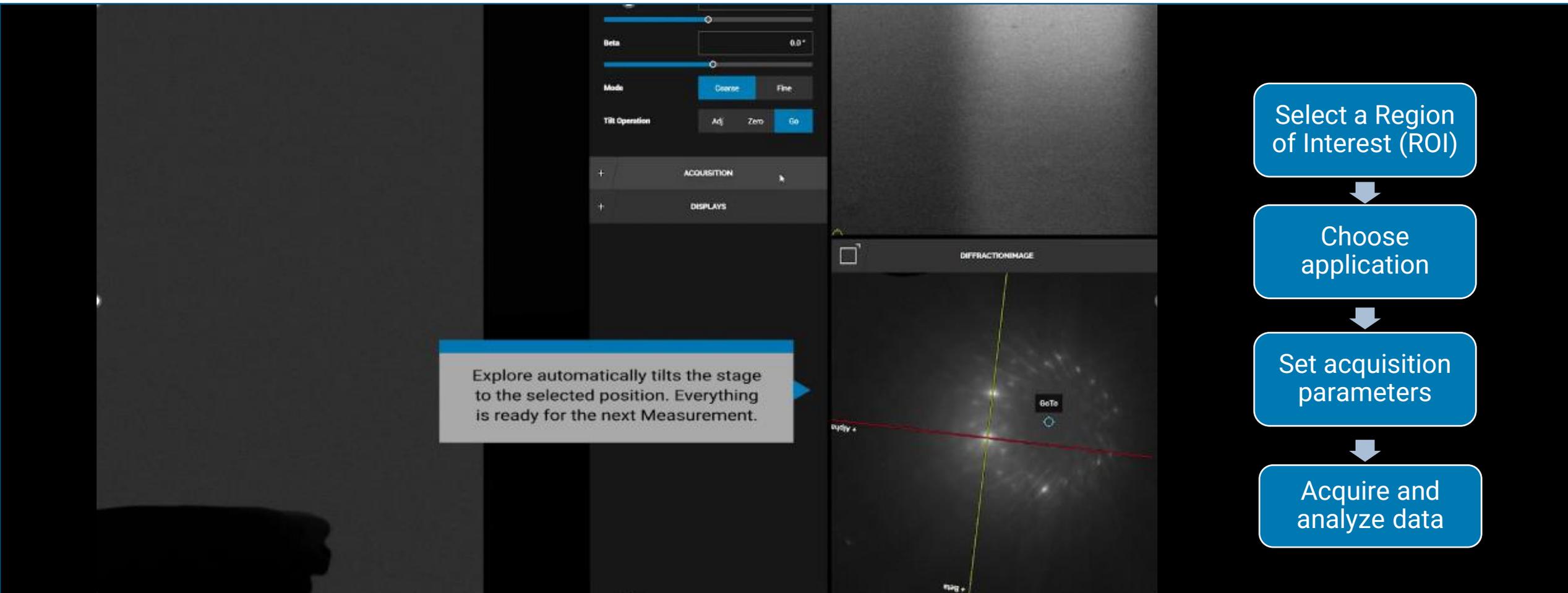
Choose application

Set acquisition parameters

Acquire and analyze data

Turning beam precession on and off

A STEM THAT IS AS EASY TO USE AS A SEM



The screenshot displays the Tescan software interface. On the left, a control panel includes a 'Beta' slider set to 0.0°, 'Mode' buttons for 'Coarse' and 'Fine', and 'TRR Operation' buttons for 'Adj', 'Zero', and 'Go'. Below these are expandable sections for 'ACQUISITION' and 'DISPLAYS'. The main area shows a 'DIFFRACTIONIMAGE' with a red horizontal line and a yellow vertical line intersecting at a central spot labeled 'BeTe'. A text box points to the interface with the text: 'Explore automatically tilts the stage to the selected position. Everything is ready for the next Measurement.'

Select a Region of Interest (ROI)

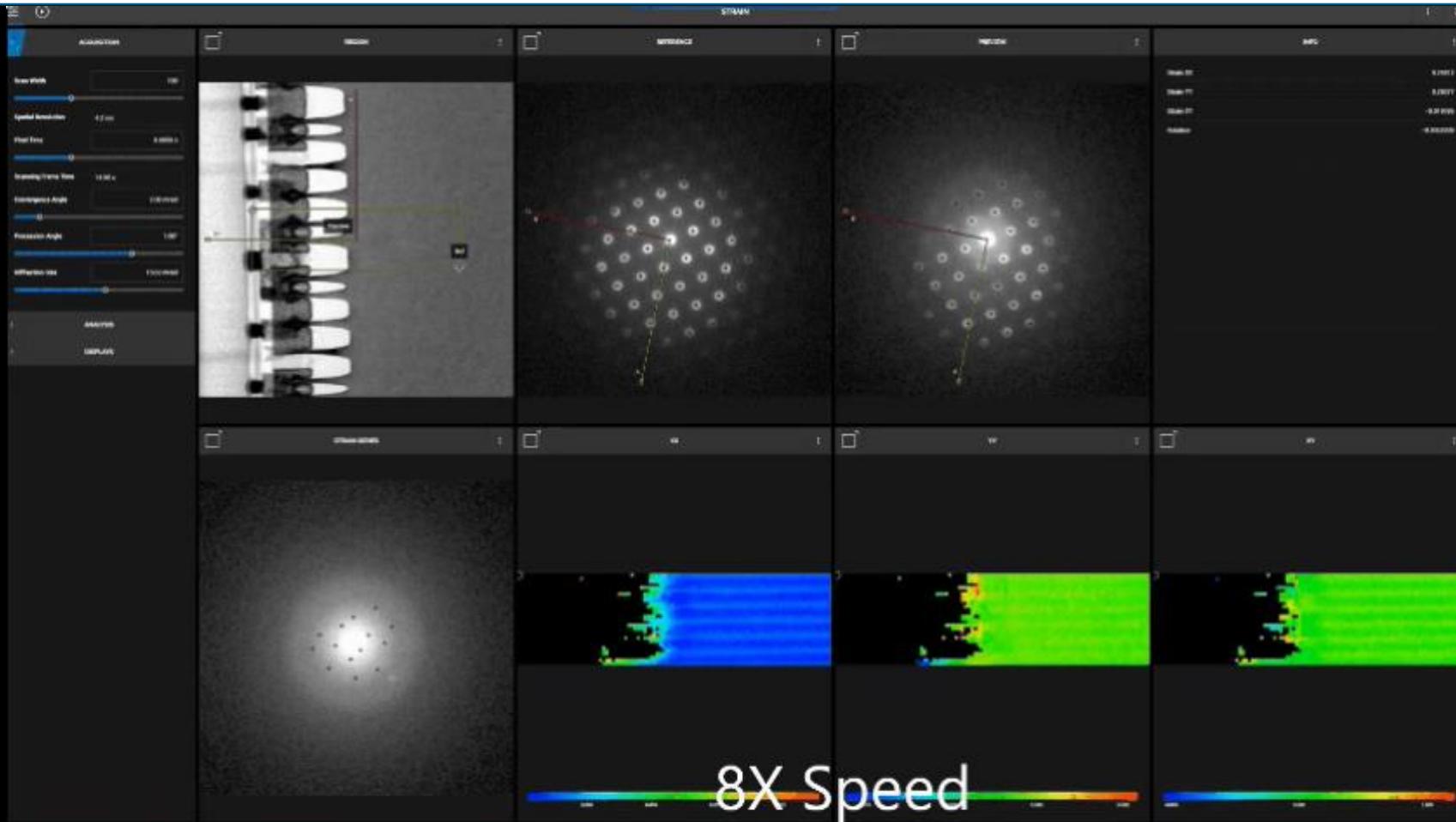
Choose application

Set acquisition parameters

Acquire and analyze data

Aligning the sample to a zone axis

A STEM THAT IS AS EASY TO USE AS A SEM



Select a Region of Interest (ROI)

Choose application

Set acquisition parameters

Acquire and analyze data

MULTIMODAL IMAGING AND ANALYTICAL TECHNIQUES

STEM Imaging (BF, ADF & HAADF)

EDS Analysis and Elemental Mapping

4D-STEM Orientation/Phase Mapping

4D-STEM Strain Mapping

Virtual STEM & Data Export

STEM Lattice Imaging

STEM Tomography

EDS Tomography

Diffraction Tomography

API for Custom Experiments

TESCAN TENSOR



THANK YOU!

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Lars Oliver Kautschor <lars-oliver.kautschor@tescan.com>

